

IN THE SPECIFICATION

Please amend the abstract at page 13 as follows:

An electro-statically actuated switch having a reduced gap distance between electrodes for reducing actuation voltage is provided. The invention provides more reliable electro-statically actuated switches. The present invention relates to The invention provides a micro-electro-mechanical system (MEMS). The present invention further relates to that includes a recessed, movable electrode. The invention provides electro-statically actuated switches that reduce the likelihood of stiction and beam deformation and that allows lower actuation voltage for electrostatically actuated structures (i.e., switches or mirrors), such as switches and mirrors. The present invention further relates to a A method for fabricating such a design is provided that allows lower actuation voltage.